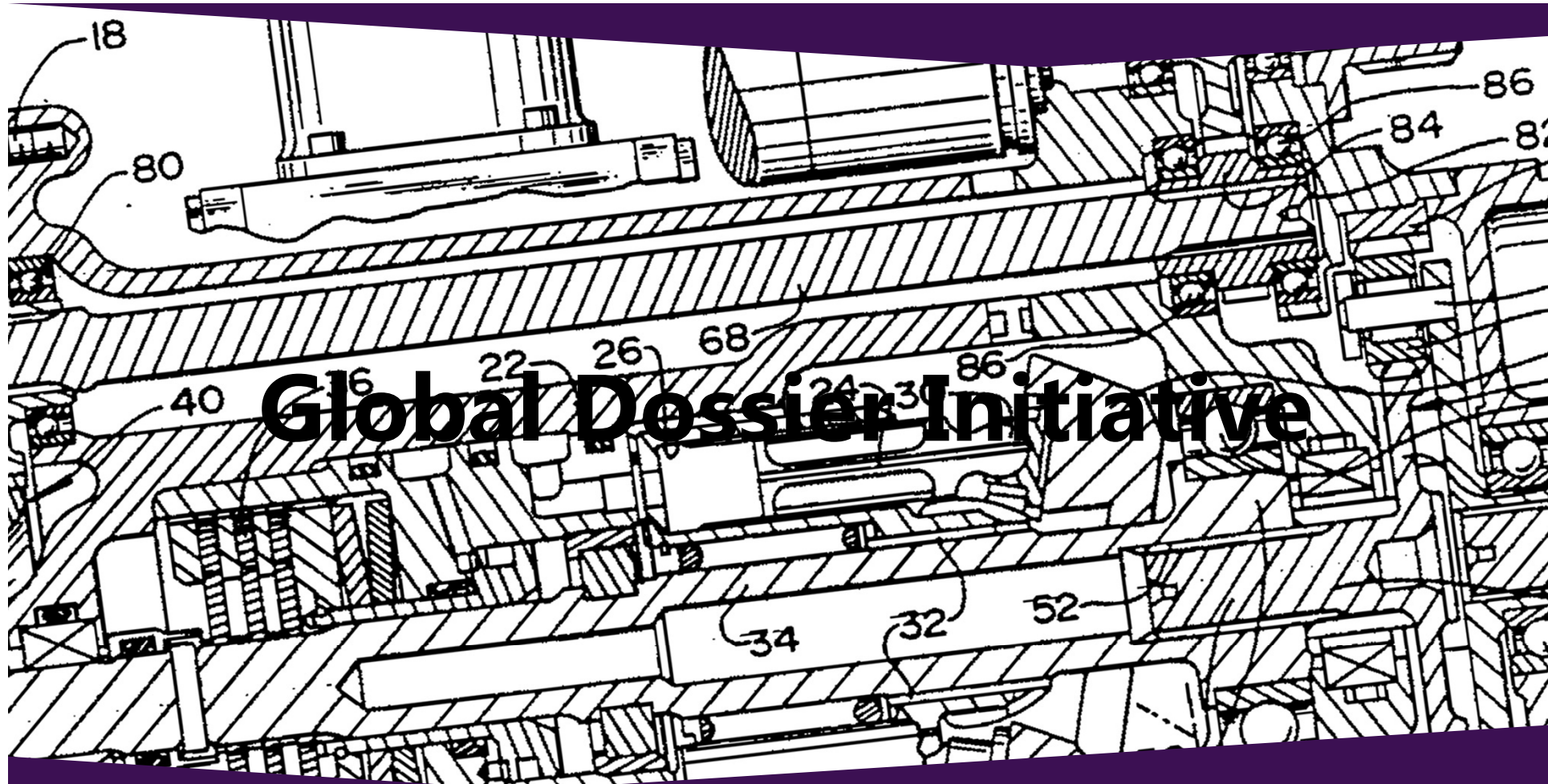


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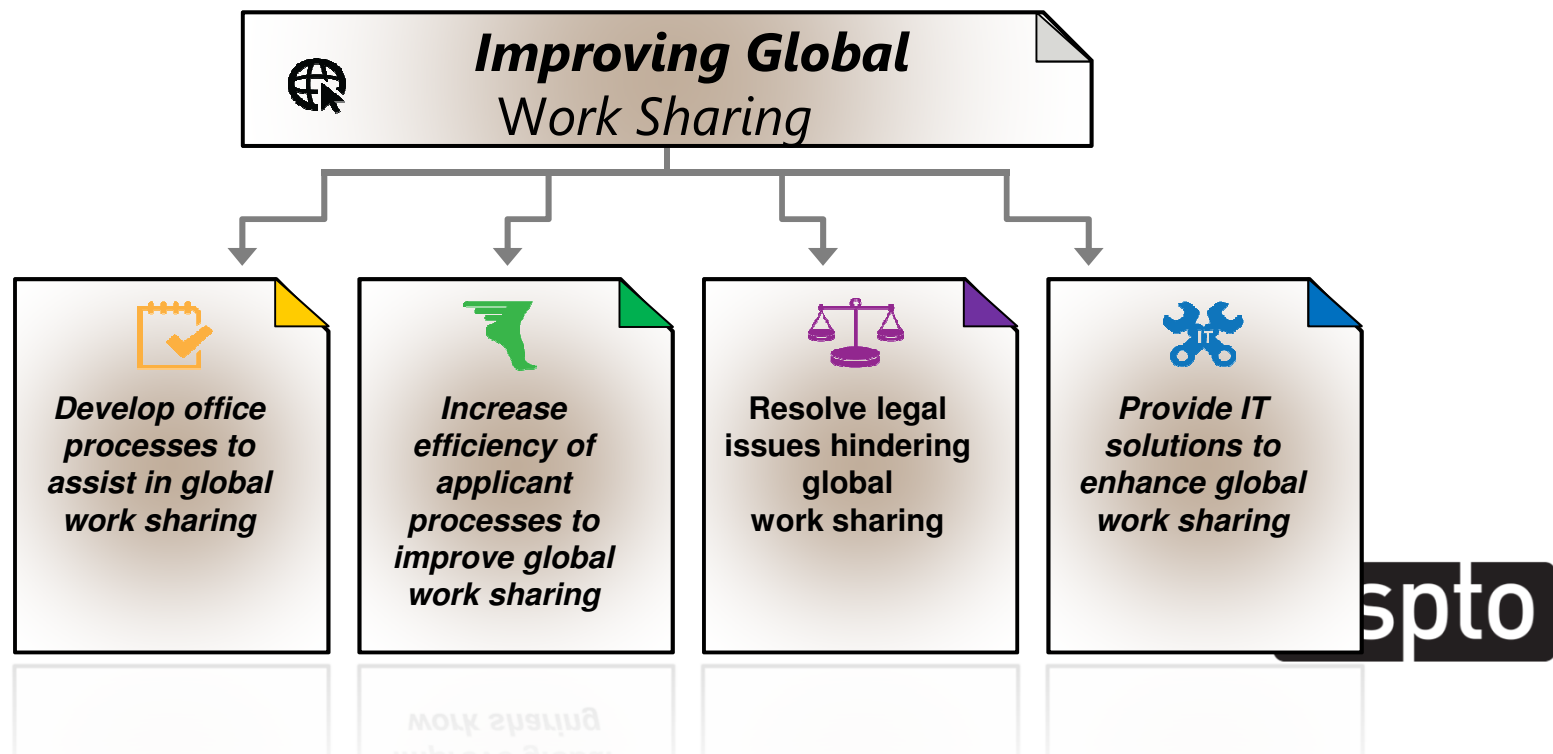
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  - Bilateral
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# The IP5

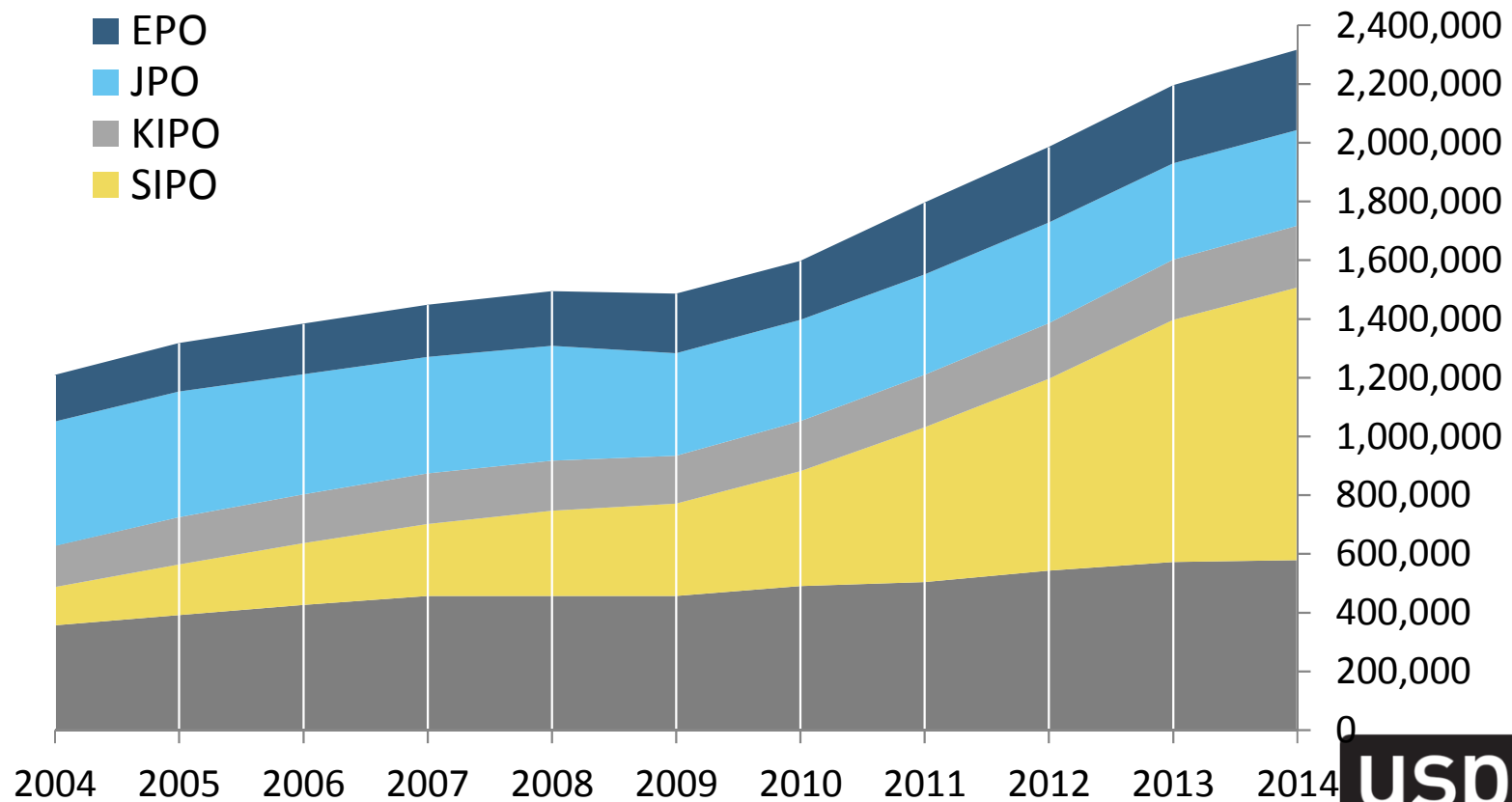
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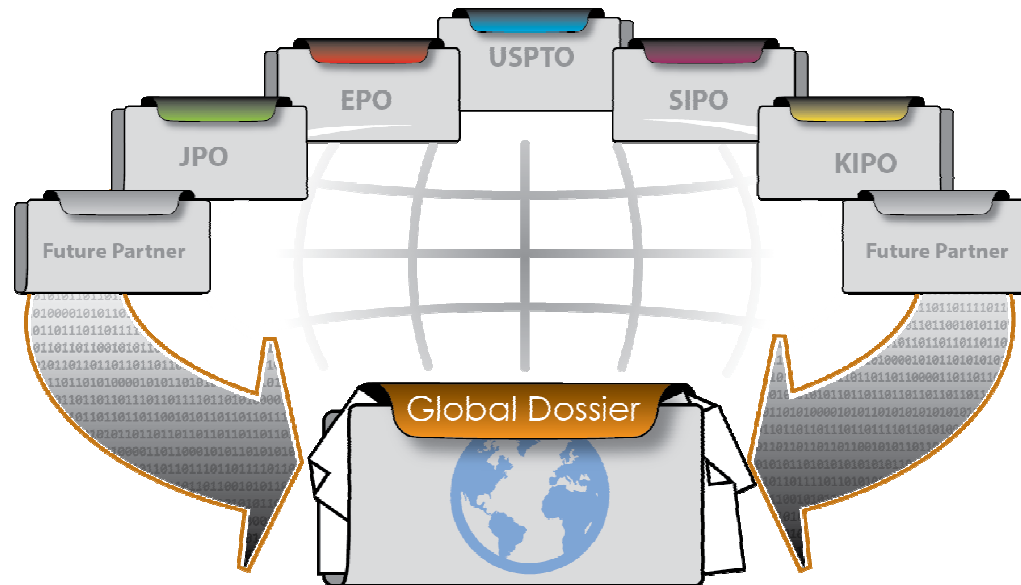
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Office: US Type: Application 13565455

**US 13565455** 9 Members in Patent Family (8 currently shown)

Office	Application	Applicant	Title	App. Date	Priority #	Pub. Date	Action
US	PCT/US09/54677	4) Eberspacher, Chris	Laser material removal methods and apparatus	08/21/2009	US 9204408	WO 2010027712 A3	05/14/2010
EP	2329518 A2			06/08/2011			(1) Add to ★
US	20100055901 A1			03/04/2010			(1) Add to ★
US	8258426 B2			09/04/2012			
CN	103537811 A			01/29/2014			(1) Add to ★
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<input checked="" type="checkbox"/> All IP5 Offices	EP	09811971 <a href="#">View Dossier</a>	1) Applied Materials, Inc.,	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 9204408 US PCT/US09/54677	EP 2329518 A2	06/08/2011	(1) <a href="#">Add to ★</a>
<input checked="" type="checkbox"/> EPO	US	12545488 <a href="#">View Dossier</a>	1) Zhang, Zhenhua 2) Rana, Virendra V.S. 3) Shah, Vinay K. 4) Eberspacher, Chris	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 9204408	US 20100055901 A1 US 8258426 B2	03/04/2010 09/04/2012	(1) <a href="#">Add to ★</a>
<input checked="" type="checkbox"/> SIPO	CN	201310590403 <a href="#">View Dossier</a>	1) APPLIED MATERIALS, INC.,	Laser material removal methods and apparatus	08/21/2009	US 9204408	CN 103537811 A	01/29/2014	(1) <a href="#">Add to ★</a>
<input checked="" type="checkbox"/> KIPO	CN	200980133793 <a href="#">View Dossier</a>	1) The Applied Materials,	Laser material removal methods and apparatus	08/21/2009	US 9204408			
<input checked="" type="checkbox"/> JPO	KR	20117006576 <a href="#">View Dossier</a>	1) Applied Materials, Inc.,	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 9204408			
<input checked="" type="checkbox"/> USPTO	JP	2011525114 <a href="#">Refresh Dossier</a>							
<input type="checkbox"/> Non-IP5 Offices	US	13565455 <a href="#">View Dossier</a>	1) ZHANG, ZHENHUA 2) Rana, Virendra V.S. 3) Shah, Vinay K. 4) Eberspacher, Chris	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 9204408			

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(1 of 1)

**United States Patent Application** 20100055901  
**Kind Code** A1  
**Zhang; Zhenhua ; et al.** March 4, 2010

**LASER MATERIAL REMOVAL METHODS AND APPARATUS**

**Abstract**

Embodiments of the present invention generally provide methods and apparatus for material removal using lasers in the fabrication of solar cells. In one embodiment, an apparatus is provided that precisely removes portions of a dielectric layer deposited on a solar cell substrate according to a desired pattern and deposits a conductive layer over the patterned dielectric layer. In one embodiment, the apparatus also removes portions of the conductive layer in a desired pattern. In certain embodiments, methods for removing a portion of a material via a laser without damaging the underlying substrate are provided. In one embodiment, the intensity profile of the beam is adjusted so that the difference between the maximum and minimum intensity within a spot formed on a substrate surface is reduced to an optimum range. In one example, the substrate is positioned such that the peak intensity at the center versus the periphery of the substrate is lowered. In one embodiment, the pulse energy is improved to provide thermal stress and physical lift-off of a desired portion of a dielectric layer.

**Inventors:** Zhang; Zhenhua; (Newark, CA); Rana; Virendra V.S.; (Los Gatos, CA); Shah; Vinay K.; (San Mateo, CA); Eberspacher; Chris; (Palo Alto, CA)

**Correspondence Address:** PATTERSON & SHERIDAN, LLP - APPM/TX  
3040 POST OAK BOULEVARD, SUITE 1500  
HOUSTON  
TX  
77056  
US

**Assignee:** APPLIED MATERIALS, INC.  
Santa Clara  
CA

**Family ID:** 41726084  
**Appl. No.:** 12/545488  
**Filed:** August 21, 2009

**Publication Link**

Related U.S. Patent Documents

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US	PCT/US09/54677			08/21/2009	US 61092044	WO 2010027712 A2 WO 2010027712 A3	03/11/2010 05/14/2010	
EP	09811971	1) Applied Materials, Inc.	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 61092044 US PCT/US09/54677	EP 2329518 A2	06/08/2011	(1) Add to ★

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**DATE DOCUMENT DESCRIPTION OPTIONS**

DATE	DOCUMENT DESCRIPTION	OPTIONS
Apr 28, 2015	Claims (ORIGINAL)	...
Apr 28, 2015	Argument (TRANSLATED)	...
Apr 28, 2015	Argument (ORIGINAL)	...

**All Documents Classification and Citation**

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**First Office Action (TRANSLATED)**

The State Intellectual Property Office of People's Republic of China

**200233**  
上海桂平路435号 上海专利商标事务所有限公司  
陆磊

Issuing Date:

Application No. or Publication Issue No.:  
**No. 201310590403.1**

Applicant Patentee: APPLIED MATERIALS, INC.

Title of Invention: Laser material removal methods and apparatus

**First Office Action**

1. Upon the request of substantive examination of the applicant, in accordance with Article 35.1 of the Patent Law, the State Intellectual Property Office performs the substantive examination for the aforesaid application for a patent for invention.

In accordance with Article 35.2 of the Patent Law, the State Intellectual Property Office proceeds to examine the aforesaid application for a patent for invention as to its substance on its own initiative.

2. The applicant requests on the basis of:



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Office	Application	Applicant	Title	App. Date	Pub. Date	Action
US	PCT/US09/54677 Refresh Dossier			08/21/2009		
EP	09811971	1) Applied Materials, Inc.,	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	03/11/2010 05/14/2010	(1) Add to ★
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	Mar 11, 2015	CDS Clean up - amended data concerning the representative of the applicant (Association)	...			
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US	12545488	1) Zhang, Zhenhua 2) Rana, Virendra V.S. 3) Shah, Vinay K. 4) Eberspacher, Chris	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	03/04/2010 09/04/2012	(1) Add to ★
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	All Documents Classification and Citation					
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	DATE	DOCUMENT DESCRIPTION ⓘ	VIEW MORE			
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	Apr 28, 2015	Argument (TRANSLATED)	...			
	Apr 28, 2015	Argument (ORIGINAL)	...			
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CN	200980133793	1) The Applied Materials,	Laser material removal methods and apparatus	08/21/2009	07/20/2011 12/11/2013	(2) Add to ★
	US 9204408 US PCT/US09/54677	CN 102132378 A CN 102132378 B				

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US 12545488 ★  
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Abstract ★  
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Office	Application	Applicant	Title	App. Date	Priority #	Pub. #	Pub. Date	Action
US	PCT/US09/54677 Refresh Dossier			08/21/2009	US 9204408	WO 2010027712 A2 WO 2010027712 A3	03/11/2010 05/14/2010	
EP	09811971	1) Applied Materials, Inc.	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 9204408 US PCT/US09/54677			
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US	12545488	1) Zhang, Zhenhua 2) Rana, Virendra V.S. 3) Shah, Vinay K. 4) Eberspacher, Chris	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 9204408			
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### History

Application

US 13565455  
EP 09811971

Publication

US 20070155322

History of viewed applications

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Application Number US 12545488

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US 12545488 (US 20100055901 A1, 8258426 B2) 67 documents

Notice of Allowance and Fees Due (PTOL-85)

Group Title Date Code Options

unknown	Issue Notification	08/15/2012	ISSUENTF	...
4	Issue Fee Payment (PTO-85B)	08/01/2012	IFEE	...
5	Fee Worksheet (S806)	08/01/2012		...
2	EFS Acknowledgment Receipt	08/01/2012		...
102	Search information including classification, databases and other search related notes	07/06/2012		...
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5	Examiner's search strategy and results	07/06/2012	SRNT	...
101	List of References cited by applicant and considered by examiner	07/06/2012	1449	...
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5	Index of Claims	07/06/2012	FWCLM	...
102	Issue Information including classification, examiner, name, claim, renumbering, etc.	07/06/2012	IFW	...
4	Bibliographic Data Sheet	07/06/2012	BIB	...
5	Examiner's search strategy and results	07/06/2012	SRNT	...
5	Fee Worksheet (S806)	04/27/2012	WFEE	...
2	EFS Acknowledgment Receipt	04/27/2012	N417	...
4	Response to Election / Restriction Filed	04/27/2012	ELC	...
4	Applicant Arguments/Remarks Made in an Amendment	04/27/2012	REM	...
1	Claims	04/27/2012	CLM	...

US 12545488  
EP 09811971  
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CN 201310590403  
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44237 7590 07/06/2012  
PATTERSON & SHERIDAN, LLP - - APPM/TX  
3040 POST OAK BOULEVARD, SUITE 1500  
HOUSTON, TX 77056

EXAMINER  
TRINIS, MICHAEL MANSI  
ART UNIT PAPER NUMBER  
2822  
DATE MAILED: 07/06/2012

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
12545488	08/21/2009	Zhenhua Zhang	013818E/SOLAR-CESONG	1445

TITLE OF INVENTION: LASER MATERIAL REMOVAL METHODS AND APPARATUS

APPL. TYPE	SMALL ENTITY	ISSUE FEE DUE	PUBLICATION FEE DUE	PREV. PAID ISSUE FEE	TOTAL FEES DUE	DATE DUE
nonprovisional	NO	\$1740	\$300	\$0	\$2040	10/09/2012

THE APPLICATION IDENTIFIED ABOVE HAS BEEN EXAMINED AND IS ALLOWED FOR ISSUANCE AS A PATENT. PROSECUTION ON THE MERITS IS CLOSED. THIS NOTICE OF ALLOWANCE IS NOT A GRANT OF PATENT RIGHTS. THIS APPLICATION IS SUBJECT TO WITHDRAWAL FROM ISSUE AT THE INITIATIVE OF THE OFFICE OR UPON PETITION BY THE APPLICANT. SEE 37 CFR 1.513 AND MPEP 1368.

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**IPC8**

H01L 21/027

H01L 31/042

**CPC**

B23K 26/0853

B23K 26/0807

B23K 26/4075

B23K 26/03

H01L 31/18

B23K 26/0635

H01L 31/022425

No matching citation data found

B23K 26/0846	....	{for moving elongated workpieces longitudinally, e.g. wire or strip material}
B23K 26/0853	...	{Devices involving movement of the workpiece in at least in two axial directions, e.g. in a plane}
B23K 26/0861	....	{in at least in three axial directions}

Classification Description

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- Strategy Targeting Organized Piracy



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# Global Dossier Citations

uspto Global Dossier

Home Public Pair Common Citation Document Current Service Status Service Hours Help

Application Number US 12545488 Patent Family All Documents Classification and Citation Collections 0 History 3

Classification Data ⓘ ⬇

**IPC8**

B23K 26/38 B05C 11/00 H01L 21/30

Citation Data ⬇

CITED BY	CITED IN	PUBLICATION/PATENT NUMBER ⓘ
applicant		US20090162972/A1
applicant		US20100055901/A1
applicant		US20100067920/A1
examiner		US20070232009/A1
examiner		US20090321109/A1
examiner		US6300593/B1
examiner		US7259321/B1
examiner		US7353076/B1
examiner		US7880155/B1
applicant		US20060196536/A1
applicant		US20010037823/A1
applicant		US20020117199/A1
applicant		US20030044539/A1
applicant		US20030129810/A1
applicant		US20060103371/A1
applicant		US20080012189/A1
applicant		US20080105295/A1
applicant		US20080115827/A1
applicant		US20090000108/A1
applicant		US20090077805/A1
applicant		US4144493/B1

View Full Patent Family

View Application Dossier

View Publication

# Global Dossier Availability

The screenshot displays the USPTO Global Dossier interface. At the top, a navigation bar includes links for Home, Public Pair, Common Citation Document, Current Service Status, Service Hours, Help, and Email Us. A red banner at the top left indicates "Current Outages" for JPO OPD Dossier Access Services. Below this, a search bar is visible. The main content area features a "Welcome to Global Dossier" message and a "Service Availability Status" modal window. This modal window shows the status for USPTO, EPO, JPO, KIPO, and SIPO, with a "Check Availability" button. A "Service Hours" modal window is also open, displaying a table of service hours for each office. The table includes columns for the day of the week, time ranges, and service types (Patent Family Service, Dossier Content Service, and Classification & Citation Service). Red text with an asterisk indicates scheduled outage hours.

**Current Outages**

- JPO OPD Dossier Access Services are down for scheduled maintenance

**Service Availability Status**

Offices: ☒ USPTO ☐ EPO ☐ JPO ☐ KIPO ☐ SIPO

[Check Availability](#)

**SERVICE AVAILABILITY STATUS FOR -- USPTO**

	Patent Family	Dossier Content	Classification & Citation
Actual	UP	UP	UP
Scheduled	UP	UP	UP

**Service Hours**

The Scheduled Outage Hours (EST/EDT) are displayed in red text indicated by an asterisk (\*). The scope of available document range coverage for EPO is from January 6, 1978 onwards.

	Patent Family Service	Dossier Content Service	Classification & Citation Service
MONDAY	00:00 - 11:00 11:00 - 12:00* 12:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 11:00 11:00 - 12:00* 12:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
TUESDAY	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
WEDNESDAY	00:00 - 11:00 11:00 - 12:00* 12:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 11:00 11:00 - 12:00* 12:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
THURSDAY	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
FRIDAY	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
SATURDAY	00:00 - 23:00 23:00 - 23:59*	00:00 - 23:59	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
SUNDAY	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59

# Upcoming Features

- Enhanced Office Action indicator
- Document filtering
- Enhanced Office availability alerts
- Linkage with WIPO CASE
- PPH pilot



# IP5 Priorities for Global Dossier

- USPTO – “Proof-of-Concept for Inter-Office Exchange”
  - Sharing documents between offices including for example, prior art exchanges, bib data updates, and supporting documents. Viewed as a first step towards cross-filing
- EPO – “Alerting”
  - Automated mechanism whereby each office alerts all the other offices, applicants, and representatives of changes in status to an application
- JPO – “XML”
  - Enabling each office, and possibly applicants and representatives, to download all application-related data from applications pending in other offices in XML format
- KIPO – “Applicant Name Standardization”
  - An automated mechanism that will assign a single, unique name to entities with applications pending in multiple office, including in instances where those entities may have used multiple names, or variations of a single name. to identify themselves
- SIPO -- “Legal Status”
  - A mechanism to allow users to view the legal status of an application in another office





# Stakeholder Input on Global Dossier

- IdeaScale - <http://uspto-globaldossier.ideascale.com/>
  - IdeaScale is one of the ways that OIPC will be gathering stakeholder input and feedback on Global Dossier.
    - Vote and comment on the various ideas
    - Provide additional suggestions for services and features that would improve the ability to monitor and manage related cases around the world
- Focus Sessions
  - Conducted to gather input and feedback on services
- Contact the Global Dossier Team
  - [GlobalDossier@USPTO.gov](mailto:GlobalDossier@USPTO.gov)



# Global Dossier Access

Direct access link:  
**<http://globaldossier.uspto.gov>**



The screenshot shows the Global Dossier website interface. At the top, there is a navigation bar with the USPTO logo and links for Home, Public Pair, Common Citation Document, Current Service Status, Service Hours, Help, Email Us, About Us, Careers, and Contact Us. Below the navigation bar is a search bar with a dropdown menu for Office (US), a dropdown menu for Type (Application), and a search input field containing 'Ex: XXXXXXXX'. To the right of the search bar are links for Collections (0) and History (0). The main content area features a welcome message 'Welcome to Global Dossier' with a globe icon. Below this are three columns of information: 'Global Dossier Initiative' (describing the initiative's goals), 'Global Dossier Public Access' (describing the service's features), and 'Service Hours' (describing the availability of the service).

**Global Dossier Initiative**

The Global Dossier Initiative is a set of business services being developed by the **IPS Offices** (USPTO, EPO, JPO, KIPO, and SIPO) aimed at modernizing the global patent system and delivering benefits to all stakeholders through a single portal/user interface. Global Dossier will provide a single, secure point of access for the management of dossier and examination information, enabling and encouraging streamlining of office procedures among different IP Offices. This will lead to improved efficiency and predictability of global patent family prosecution with increased cost savings provided to patent applicants.

For more information, on the please visit the [Global Dossier Initiative](#) page.

**Global Dossier Public Access**

The first service being provided by the Global Dossier Initiative is a secure, online access to the file histories of related applications from participating IP Offices, which currently include the IPS Offices.

By using this service, users can see the patent family for a specific application, containing all related applications filed at participating IP Offices, along with the dossier, classification, and citation data for these applications. This service also provides Office Action indicators to help users identify applications that contain office actions, a Collections View for saving documents and applications for review later on in the session, and the ability to download the documents in an application.

**Service Hours**

Global Dossier users will be able to view the scheduled service hours for each IPS office, including scheduled outages due to holidays and maintenance.

To view the scheduled hours of availability, users can select the **Service Hours** link on the top right corner of the website. In addition, any current scheduled outages for one or more offices will also be displayed on top of the homepage as a reminder for the users.

Users may also verify the availability of application data from each office by selecting the **Current Service Status** link on the top right side of the website.



The footer section of the USPTO website. It features the USPTO logo and the text 'UNITED STATES PATENT AND TRADEMARK OFFICE'. Below this is a grid of links organized into four columns: 'BROWSE BY TOPIC' (Patents, Trademarks, Learning & Resources, About the USPTO, Glossary, Careers), 'ABOUT THIS SITE' (Accessibility, Privacy Policy, Terms of Use, Security, Systems Status, Site Map), 'USPTO BACKGROUND' (Federal Activity Inventory Reform Act (FAIR), USPTO Budget and Performance, Freedom of Information Act, Information Quality Guidelines), and 'FEDERAL GOVERNMENT' (Regulations.gov, StopFakes.gov, USA.gov, Department of Commerce, Strategy Targeting Organized Piracy). To the right of the grid is a large USPTO logo.

**uspto** UNITED STATES PATENT AND TRADEMARK OFFICE

**BROWSE BY TOPIC**

- Patents
- Trademarks
- Learning & Resources
- About the USPTO
- Glossary
- Careers

**ABOUT THIS SITE**

- Accessibility
- Privacy Policy
- Terms of Use
- Security
- Systems Status
- Site Map

**USPTO BACKGROUND**

- Federal Activity Inventory Reform Act (FAIR)
- USPTO Budget and Performance
- Freedom of Information Act
- Information Quality Guidelines

**FEDERAL GOVERNMENT**

- Regulations.gov
- StopFakes.gov
- USA.gov
- Department of Commerce
- Strategy Targeting Organized Piracy

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# Global Dossier Contacts

E-mail: [GlobalDossier@USPTO.gov](mailto:GlobalDossier@USPTO.gov)

**Don Levin**

Director, International Patent Business Solutions

571-272-3785

[Don.Levin@USPTO.gov](mailto:Don.Levin@USPTO.gov)

**Nelson Yang**

Patent Business Analyst, International Patent Business Solutions

571-272-0826

[Nelson.Yang@USPTO.gov](mailto:Nelson.Yang@USPTO.gov)

**Jessica Patterson**

Program Manager, Office of International Patent Cooperation

571-272-8828

[Jessica.Patterson@USPTO.gov](mailto:Jessica.Patterson@USPTO.gov)



